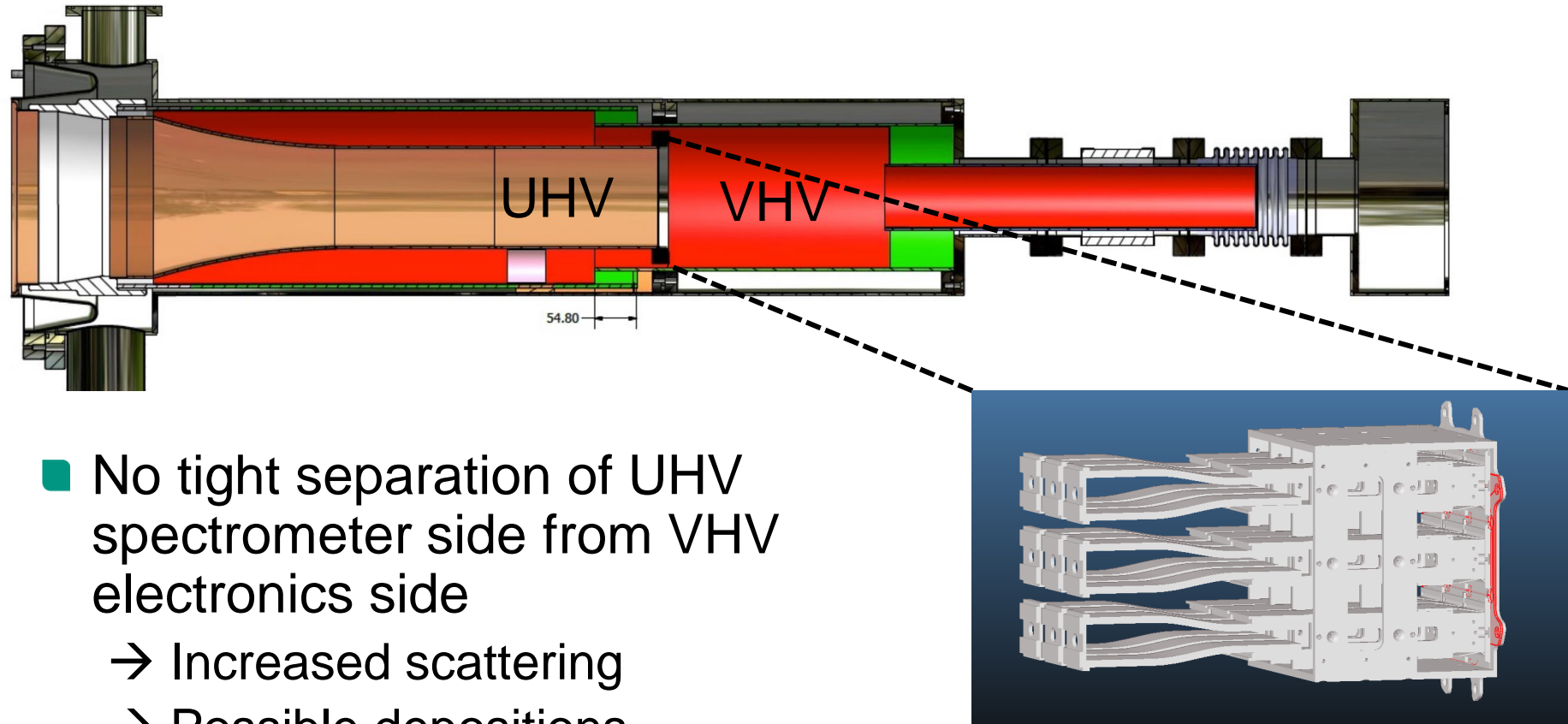


# Vacuum Investigations

## Phase-1 vacuum conductance simulations

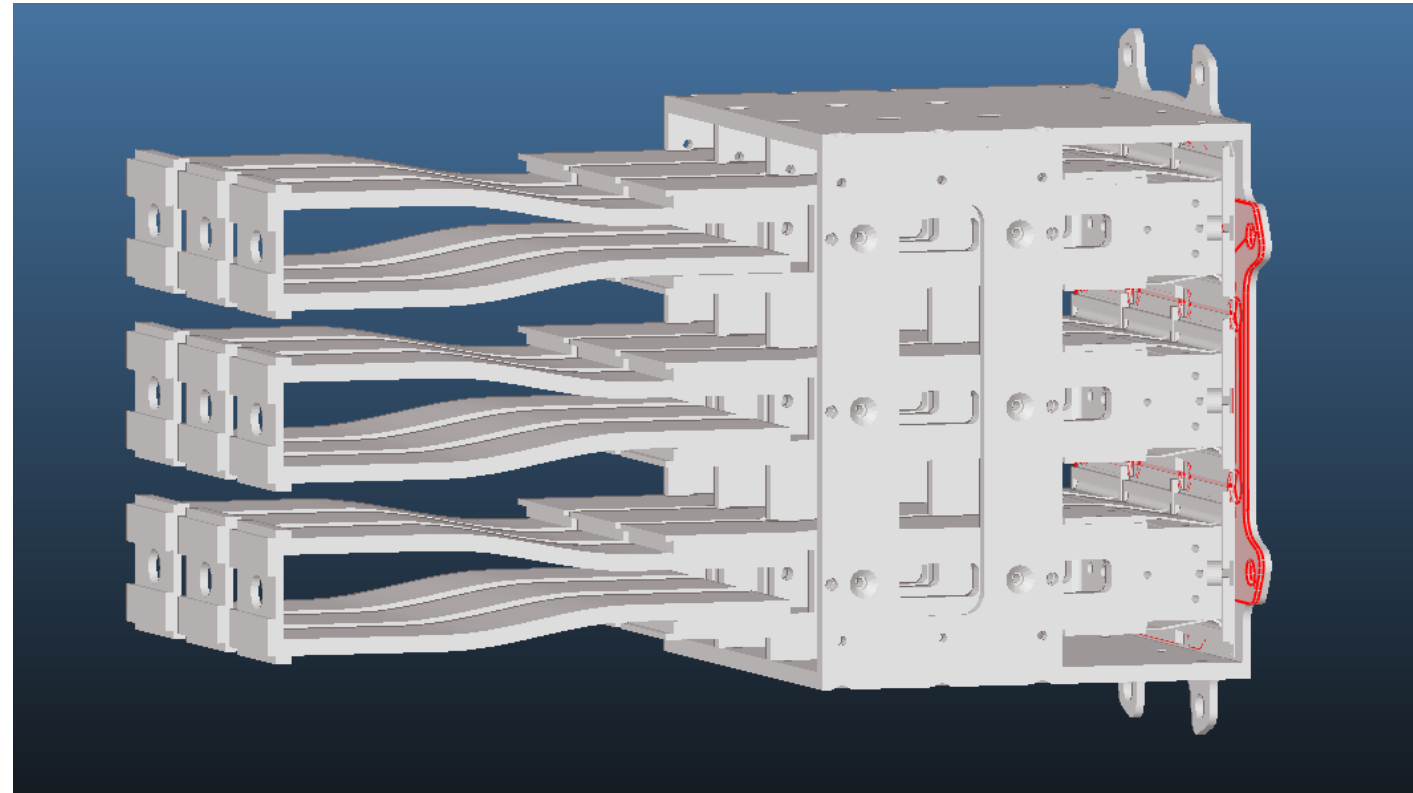
# Importance of vacuum compatibility



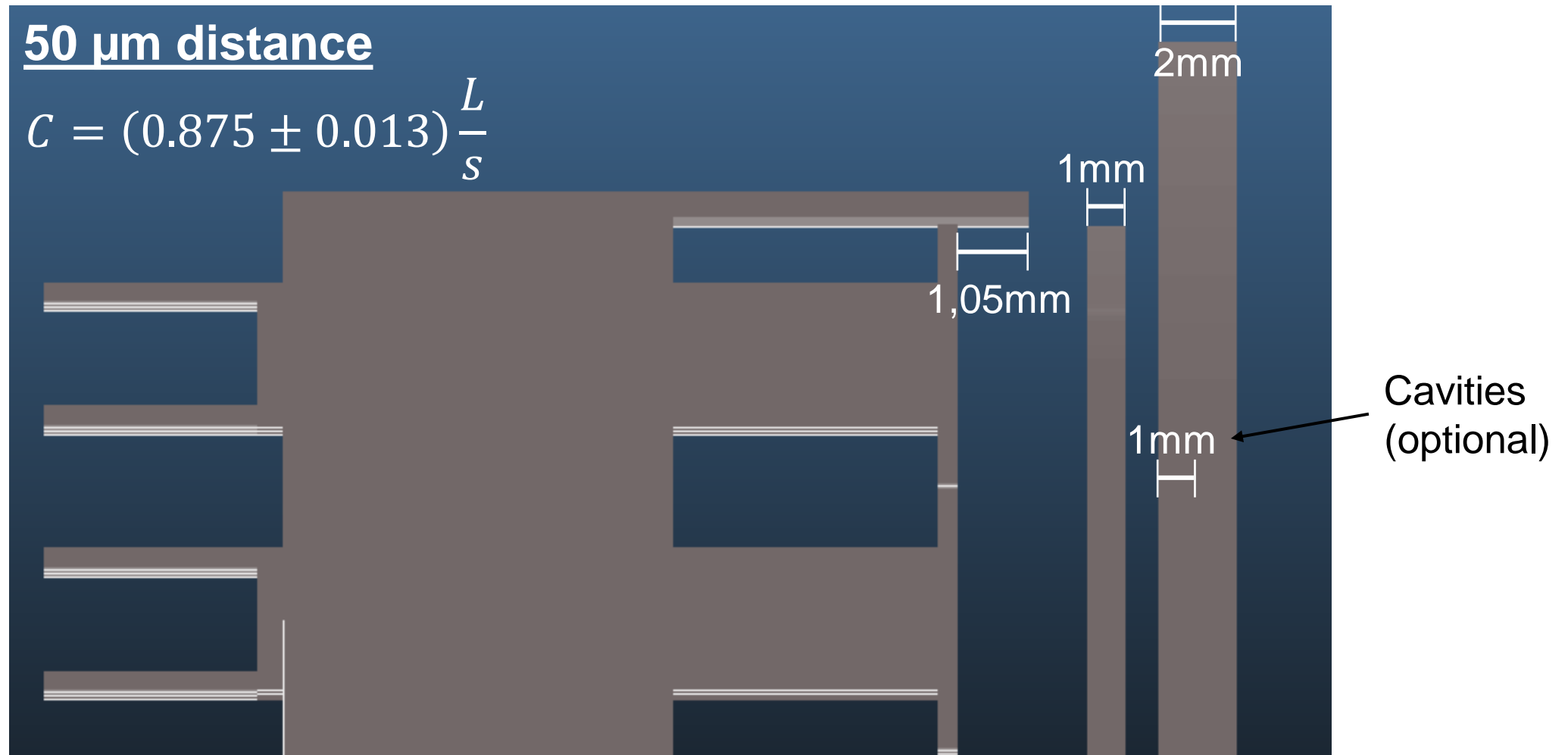
- No tight separation of UHV spectrometer side from VHV electronics side
  - Increased scattering
  - Possible depositions

# Vacuum shield design

- Shielding split in two parts
  - part of detector mounting
  - thickness partly adjustable
  - Adjustable material selection (stainless steel, kapton, combination)
- Design distance aim  $d=50\mu\text{m}$

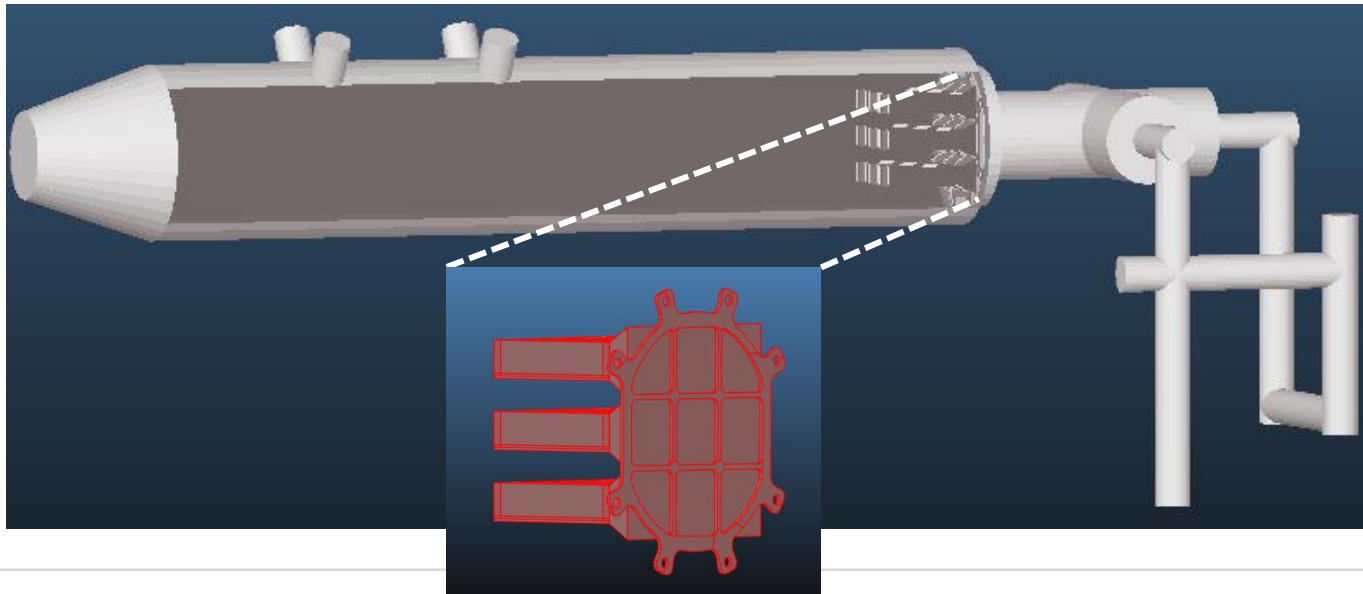


# Vacuum shield design



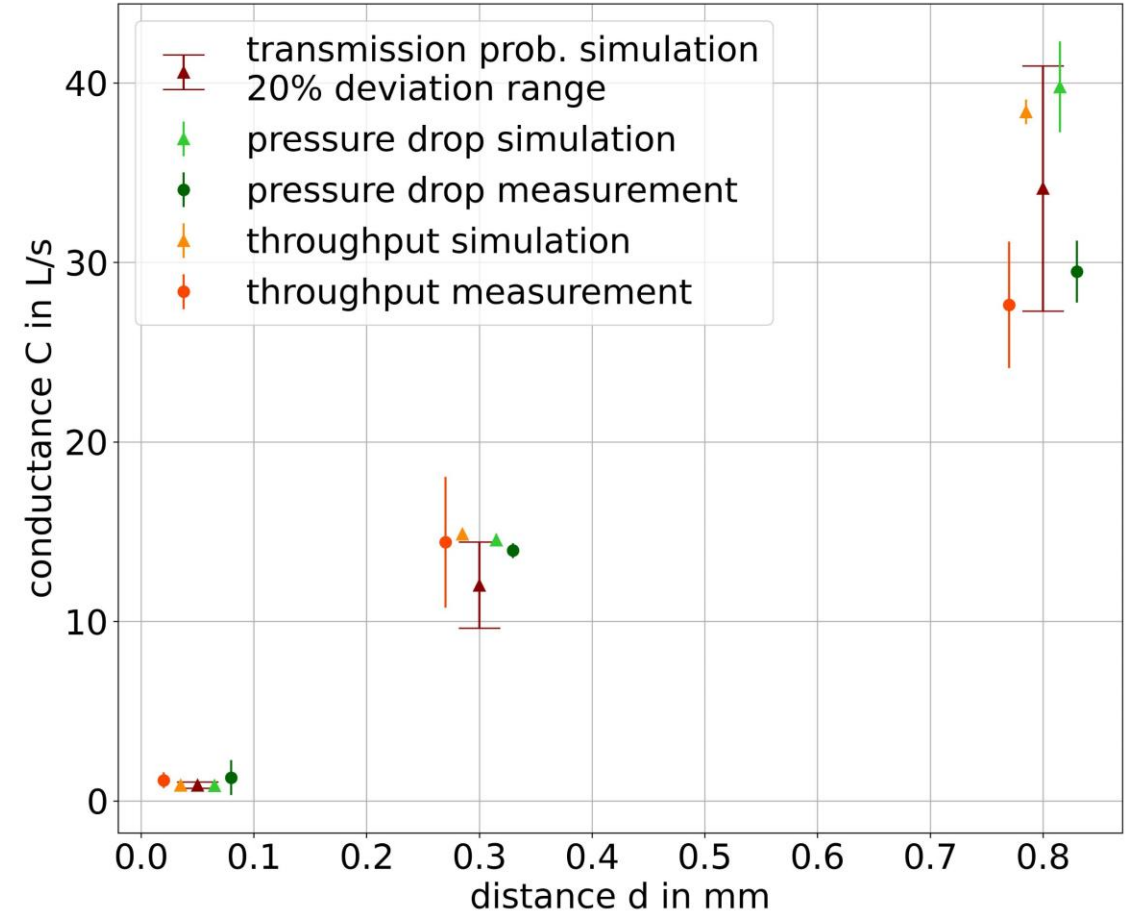
# Measurement setup

- Dedicated setup to determine detector conductance
- 2 independent measurement methods
  - +1 simulation method



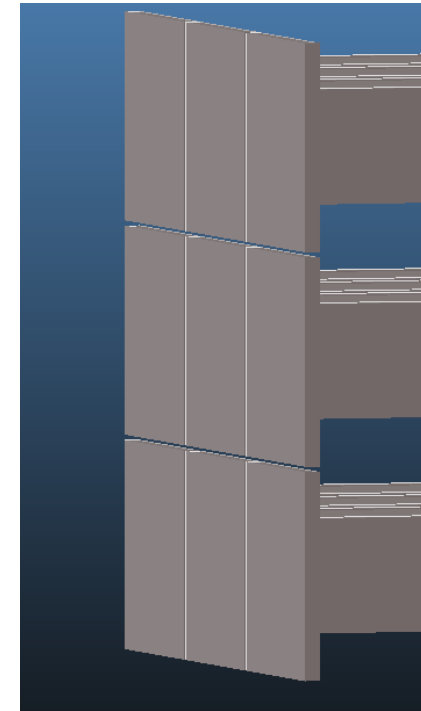
# Conductance measurements

- Simulations in agreement with measurements
- Design distance of 0.05 mm in desired range of  $\sim 1$  L/s
- Strong dependency on distance

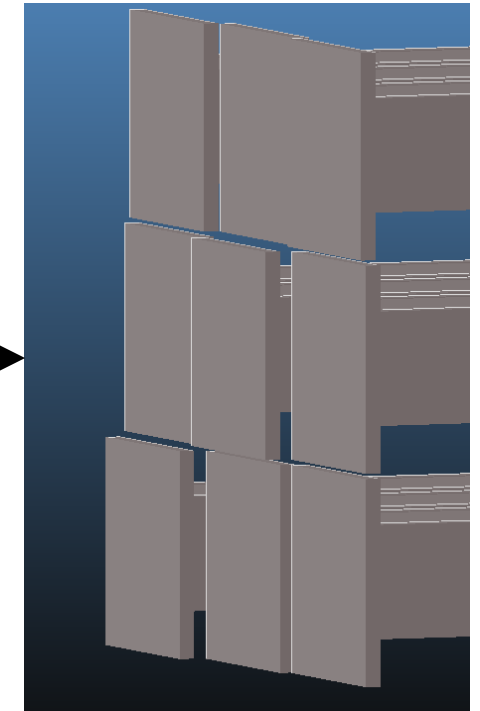


# Gluing induced distance deviations

- Investigation of module positioning



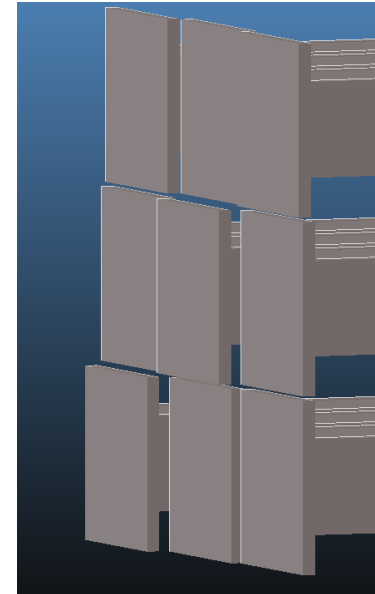
-50 $\mu$ m  
design distance



$\pm$ 50 $\mu$ m  
random deviations

# Gluing induced distance deviations

- Investigation of module positioning
- determine conductance for
  - 1) Random offset



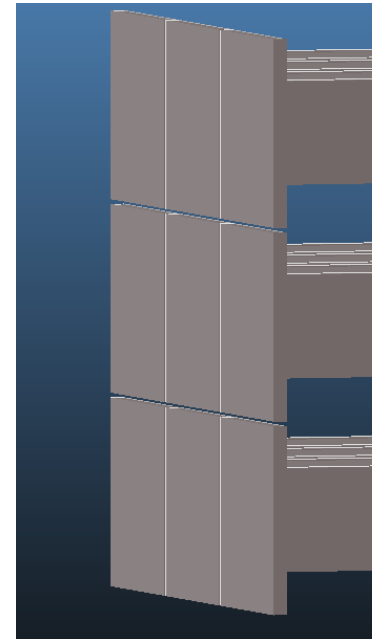
-20	-50	-30
-10	+10	-40
+30	-20	-40

Added to  $-50\mu\text{m}$   
design distance

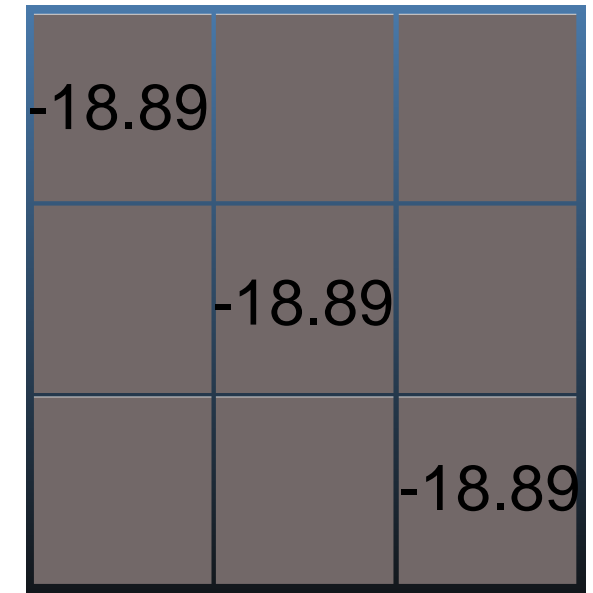


# Gluing induced distance deviations

- Investigation of module positioning
- determine conductance for
  - 1) Random offset
  - 2) Mean added distance



Mean: 68.89  $\mu\text{m}$



Added to  $-50\mu\text{m}$   
design distance

# Gluing induced distance deviations

- Investigation of module positioning
- determine conductance for
  - 1) Random offset
  - 2) Mean added distance
  - 3) High distance module @ each position

-90	-10	-10
-10	-10	-10
-10	-10	-10

Added to  $-50\mu\text{m}$   
design distance

# Gluing induced distance deviations

- Investigation of module positioning
  
- determine conductance for
  - 1) random offset
  - 2) mean added distance
  - 3) high distance module @ each position
  - 4) optimized positioning according to 3)

-40	-20	-40
+10	-20	+30
-30	-10	-50

Added to  $-50\mu\text{m}$   
design distance

# Comparison to mean distance

- Conductance compared to mean distance @68μm  $C_{mean} = 1.43 \frac{L}{s}$

$$\Delta C = \frac{C - C_{mean}}{C_{mean}}$$

- 1) Random:  $\Delta C = 0.071$  ( $C = 1.53 \frac{L}{s}$ )
- 2) Mean:  $\Delta C = 0.000$
- 3) High distance module  $\longrightarrow$
- 4) Optimized  $\Delta C = -0.012$  ( $C = 1.42 \frac{L}{s}$ )

-0.005	0.085	0.002
0.094	0.076	0.094
0.003	0.090	-0.008

- Improvement of ~8% (0.1 L/s) for optimized layout

# Relative or absolute effect

- How large is  $\Delta C = \frac{C - C_{mean}}{C_{mean}}$  for overall increased distance

Mean

-18.89		
	-18.89	
		-18.89

Random

-20	-50	-30
-10	+10	-40
+30	-20	-40

Optimized

-40	-20	-40
+10	-20	+30
-30	-10	-50

Added to -150μm distance

C in L/s: 5.26

$\Delta C$  : -

5.31

0.01

5.15

-0.02

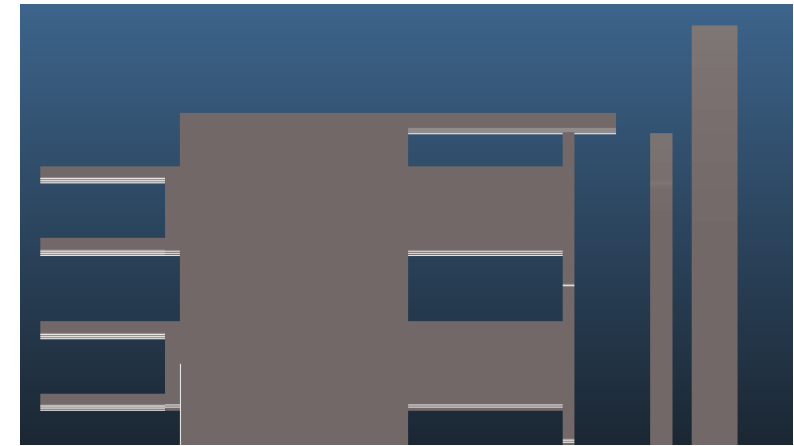
# Relative or absolute effect

- Positioning of modules is not critical
  - Improvement on absolute scale of 0.1-0.2 L/s
  
- Fluctuations in gluing thickness greatly impact conductance
  - $C(50\mu m) = 0.88 \frac{L}{s} \longrightarrow C(68\mu m) = 1.43 \frac{L}{s}$
  
- Difference in module length still valuable for detector conductance
  - Variable shield thickness can compensate some deviation

-40	-20	-40
+10	-20	+30
-30	-10	-50

# Relative or absolute effect

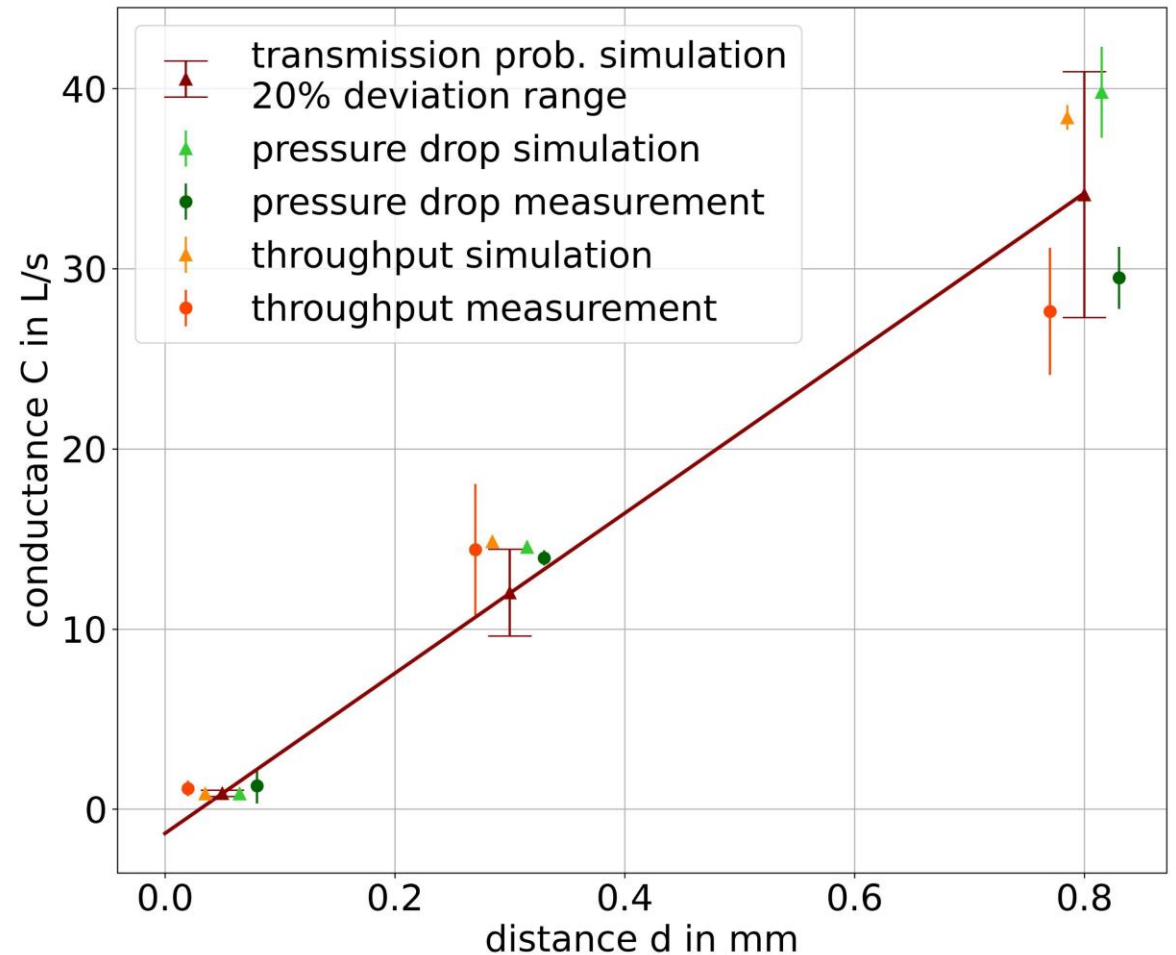
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- Difference in module length still valuable for detector conductance
  - Variable shield thickness can compensate some deviation



-40	-20	-40
+10	-20	+30
-30	-10	-50

# Conductance simulations

- Design distance of 0.05 mm in desired range of ~1 L/s
- Strong distance dependence: 4.4 L/s per 0.1 mm

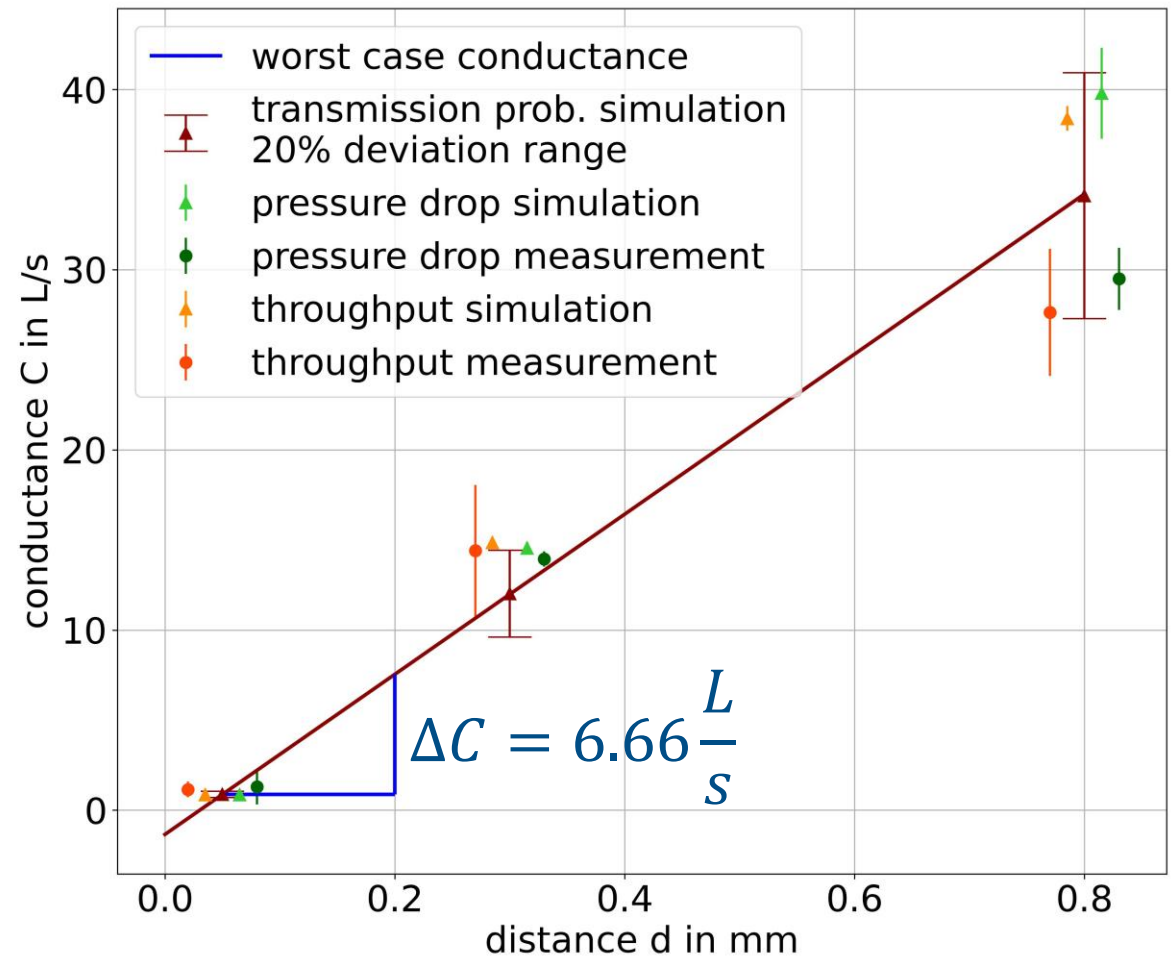




# Conductance simulations

- Design distance of 0.05 mm in desired range of ~1 L/s
- Strong distance dependence: 4.4 L/s per 0.1 mm
- Worst case feasibility estimation:
  - Production accuracy limits: 0.1 mm
  - Additional gluing layer difference: 0.05 mm

 deviations of ~1 order of magnitude possible

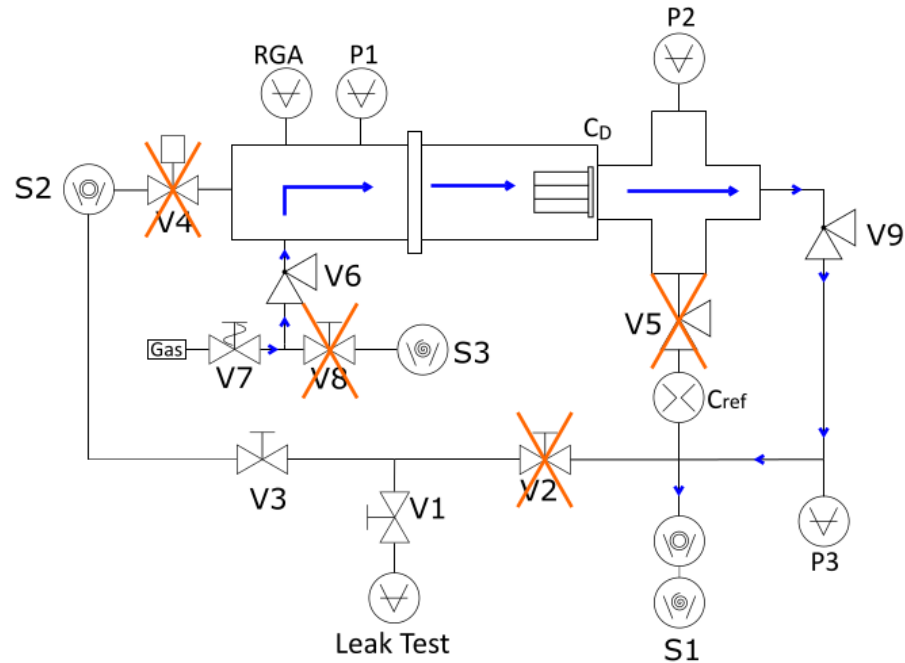


# Conclusion/Outlook

- Conductance at design distance in desired range  $\sim 1$  L/s
  - Module positioning is not critical
  - But exact module length is still beneficial
  - Very sensitive to distance changes (4.4 L/s per 0.1 mm)
- Outgassing measurements planned at KIT
- Simulation of final pressure in Main Spectrometer is being set up
- Sensitivity study for deteriorated vacuum conditions in main spectrometer

# Measurement methods

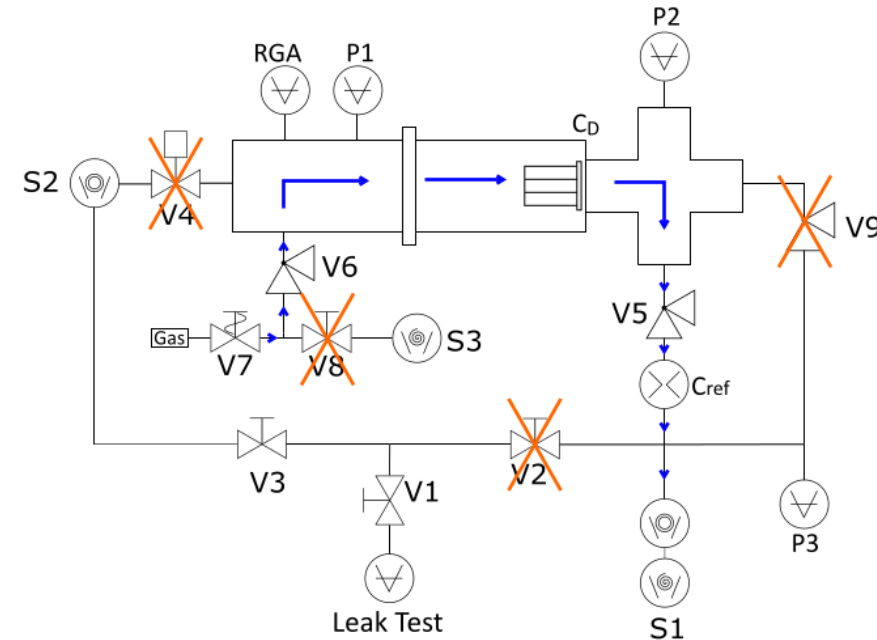
## Pressure drop



Determination of conductance via exponential pressure drop:

$$P(t) = P(0) \cdot e^{-\frac{t}{\tau}} \quad \text{with} \quad \tau = \frac{V}{S_{eff}} \approx \frac{V}{S + C_D}$$

## Throughput



Determination of conductance via pressure difference at equilibrium:

$$C_D = \frac{Q}{P_1 - P_2} \quad \text{and} \quad C_{ref} = \frac{Q}{P_2 - P_3}$$

# Measurement principle

## Transmission probability

- $C_{hole} = \frac{1}{4} \cdot A_1 \cdot \bar{c} \rightarrow C = C_{hole} \cdot \alpha$

with  $\alpha = \frac{Absorption(A_2)}{Desorption(A_1)}$

and  $\bar{c} = \sqrt{\frac{8 \cdot R \cdot T}{\pi \cdot M_{gas}}}$

